

IN THE CLAIMS

Please amend the claims as follows:

- 1 1 (Currently Amended). A microphotonic device comprising:  
2 a deformable membrane structure that can experience strain; and  
3 a waveguide element formed on said deformable membrane structure so that  
4 when said deformable membrane structure is strained, said waveguide element is tuned to  
5 a selective amount.
- 1 2 (Currently Amended). The microphotonic device of claim 1, wherein said deformable  
2 membrane structure comprises a sub-micron SiO<sub>2</sub> layer.
- 1 3 (Original). The microphotonic device of claim 1, wherein said waveguide element  
2 comprises a microring resonator.
- 1 4 (Original). The microphotonic device of claim 1, wherein said waveguide element  
2 comprises a microracetrack resonator.
- 1 5 (Original). The microphotonic device of claim 1, wherein said waveguide element  
2 comprises a 1-dimensional photonic crystal.
- 1 6 (Original). The microphotonic device of claim 1, wherein said waveguide element  
2 comprises a 2-dimensional photonic crystal.
- 1 7 (Original). The microphotonic device of claim 5, wherein said 1-dimensional photonic  
2 crystal comprises holes.

1 8 (Original). The microphotonic device of claim 7, wherein said selective amount  
2 comprises approximately 1%.

1 9 (Original). The microphotonic device of claim 3, wherein said selective amount  
2 comprises 0.2%.

1 10 (Currently Amended). The microphotonic device of claim 1 further comprising at  
2 least one piezoelectric actuator that is coupled to said deformable -membrane so as to  
3 produce said strain.

1 11 (Currently Amended). A method of forming a microphotonic device comprising:  
2 providing a deformable membrane structure that can experience strain; and  
3 forming a waveguide element on said deformable membrane structure so that  
4 when said deformable membrane structure is strained said waveguide element is tuned to  
5 a selective amount.

1 12 (Currently Amended). The method of claim 11, wherein said deformable membrane  
2 structure comprises a sub-micron SiO<sub>2</sub> layer.

1 13 (Original). The method of claim 11, wherein said waveguide element comprises a  
2 microring resonator.

1 14 (Original). The method of claim 11, wherein said waveguide element comprises a  
2 microracetrack resonator.

1 15 (Original). The method of claim 11, wherein said waveguide element comprises a 1-  
2 dimensional photonic crystal.

1 16 (Original). The method of claim 11, wherein said waveguide element comprises a 2-  
2 dimensional photonic crystal.

1 17 (Original). The method of claim 15, wherein said 1-dimensional photonic crystal  
2 comprises holes.

1 18 (Original). The method of claim 17, wherein said selective amount comprises  
2 approximately 1%.

1 19 (Original). The method of claim 13, wherein said selective amount comprises 0.2%.

1 20 (Currently Amended). The method of claim 11 further comprising providing at least  
2 one piezoelectric actuator that is coupled to said deformable membrane so as to produce  
3 said strain.